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 TI Reflecting layer of optical recording medium and sputtering
 target for forming reflecting layer
 IN Oda, Nobuhiro; Ueno, Takashi; Akimori, Toshihiro
 PA Furuya Metal Co., Ltd., Japan; Sony Corporation
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AB The invention relates to a reflecting layer of an optical recording medium having a recording layer, a reflecting layer, and a protecting layer on a substrate, wherein the reflecting layer is made of an alloy thin film comprising 99.7-73.0 weight of Cu as a primary component, 0.2-18.0 weight of Ag, and 0.1-9.0 weight of Ti and has a film thickness of 50-150 nm. A target for forming the reflecting layer is also claimed. The optical recording medium having the reflecting layer (exhibits improved resistance while retaining high reflectance).

RE.CNT 3 THERE ARE 3 CITED REFERENCES AVAILABLE FOR THIS RECORD
 ALL CITATIONS AVAILABLE IN THE RE FORMAT